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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Tsai et al.

Serial No.: 10/694,426


Filed: October 27, 2003

For: **Method of a Floating Pattern Loading System  
in Mask Dry-Etching Critical Dimension  
Control**

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)  
) Group Art Unit: 1756  
)  
) Examiner: Rosasco, Stephen D.  
)  
) Confirmation No.: 3358  
)  
) TKHR Docket: 252016-2470  
) Top-Team: 0503-A30742US  
)

Certificate of Mailing

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Mail Stop Amendment; Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, on June 17, 2005.

  
Signature – Hui Chin Barnhill

**RESPONSE TO RESTRICTION REQUIREMENTS**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

The Office Action mailed May 19, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.